C overage dependence of the 1-propanoladsorption on the Si(001) surface and fragm entation dynam ics

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Abstract

The geometric, electronic, energetic, and dynamic properties of 1-propanol adsorbed on the Si(001)-(2 1) surface are studied from rst principles by use of a slab approach. The 1-propanol molecule initially interacts with the Si surface through form ation of a dative bond, subsequently the physisorbed 1-propanolm olecule reacts with the surface by cleavage of the O-H bond, and the Si(001)-(2 1) surface undergoes further reconstruction as a result of the adsorption of the organic species. The band structure and density of states (DOS) are rst analyzed for this system. The band gap of the Si/1-propanol m increases as the coverage level is enhanced. G ood agreement is found with available experimental data.

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I. IN TRODUCTION

The chem isorption of organic molecules on silicon surfaces is a highly topical subject of current research, both experim ental and computational. This interest may be ascribed to both the fundamental nature of this problem, involving the interaction between nite units and periodic substrates, but also to its relevance to various areas of recent technology, such as insulator Im s, nanolithography, chem ical and biological sensors, and m olecular electronics. The organic layers are formed by depositing organic compounds on the sem iconductor surface. In order to optimize this process, the understanding of the interaction between the surface and the organic species is crucial. The majority of the reactions between the sem iconductor surface and organic molecules occur at or near the dangling bonds of the reconstructed surface. For a silicon (001) surface, the 2 1 reconstruction leads to the formation of silicon dimers, where a strong bond and a weak bond between the two dimer atom s is observed¹. It is well known that for hydrocarbons, the C-C double bonds break the dimer bond and lead to the form ation of the new surface bonds that are energetically favorable². Em ploying a similar mechanism, one can produce well ordered organic $\ln s/Si$ structures with a stable and uniform interface. These composites of silicon surfaces coated by organic In s m ay lead to novel types of m icroelectronic devices that exploit the rich variety of functional groups of the organic species.

In the past decade, the reaction between the silicon surface dimers and alcohols have attracted much attention³ ¹¹. For instance, the adsorption of ethanol on Si(001) was instructed by using surface infrared absorption spectroscopy⁴. At room temperature, the ethanol is adsorbed dissociatively to form surface bound hydrogen and ethoxy groups, as a consequence of 0 H bond breaking. The adsorption of ethanol on Si(001) at room temperature has also been studied employing high-resolution synchrotron radiation photoem ission⁵. In this case, 0 H bond scission occurs. This behavior is at variance with ethanol adsorption on Si(111)–(7 7)⁶, where the C-O bonds where found to be broken. The reaction of 1-propanol (C₃H₈O) with the Si(001)–(2 1) surface was investigated in the pioneering work of Zhang et al.¹¹ by A uger electron spectroscopy and them al desorption spectroscopy. From this study, the 1-propanolm olecule initially interacts with the Si surface through the form attion of a \dative bond", followed by further reaction of the physisorbed 1-propanolm olecule with the surface by 0 H bond cleavage. From the work reported in reference¹¹, the 0 H bond

cleavage is a kinetically favored reaction, but the 0-C bond cleavage is therm odynam ically preferred.

So far, there is no full st-principles theoretical calculation that provides a complete description of the 1-propanolm olecule reaction with the Si(001) surface, excepting a prelim inary calculation in the fram ework of a single-dim er cluster m odel for the Si(001) surface¹¹. A dopting the latterm odel, how ever, the surface-speci c aspects of the problem at hand cannot be treated adequately. Thus, it is in possible to simulate the \buckling" of the surface dimer. As mentioned in the work of Zhang et. al¹¹, the results based on a single-dimer m odel should be substantially in proved by considering an array of dim er clusters to account adequately for charge delocalization or surface relaxation phenom ena. Secondly, the electronic properties, such as the band structure and the density of states (DOS) distribution for this system, have not been discussed before. For in-depth analysis of the substrate-adsorbate interaction, however, the understanding of these features is of crucial in portance. Thirdly, studying the dependence of various characteristic properties on the 1-propanol coverage is hardly feasible in the framework of a single-dimermodel¹². Finally, the mechanism of the reaction between the 1-propanole molecule and the Si(001) surface has not been studied before. Such a simulation, involving the interaction of the nite molecular adsorbate and the periodic substrate at room tem perature has been perform ed in the context of the present work by means of ab initio molecular dynamics (MD), as described in further detail below.

Guided by this motivation, in the present contribution we study the adsorption of 1propanolon the Si(001)-(2 1) surface by use of the VA SP $code^{13}$, involving a slab geom etry and periodic boundary conditions. The introduced model allows for an appropriate description of the Si(001) surface with and without the adsorption of the 1-propanol molecule as the reconstruction of the Si surface before and after adsorption can be displayed manifestly. Section III of this contribution contains a detailed analysis of the most prominent reactions undergone by 1 - propanol on the Si(001) surface, including the calculations of the reaction barriers corresponding to various reaction pathways. Further, the charge density in a plane including the 1 - propanol oxygen and a surface silicon atom, the surface band structure within the silicon fundamental gap, and the DOS and partial DOS distributions projected on the substrate atom s as well as the 1-propanol molecule or its fragments are discussed. In addition, we outline the variation of the binding energies, the energy barriers, the DOS, and the energy gap with the degree of coverage, where four coverage levels (0.125 M L, 0.25M L,

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0.5M L, and 1.0M L) are taken into account. Finally, we will make admission for nite tem – perature and compare the characteristic reaction mechanism s at T = 300 K with those found at T = 0 K.

II. COMPUTATIONALMETHOD

Our calculations were carried out by use of the VASP code¹³. Density functional theory (DFT) was applied on the level of the generalized gradient approximation $(GGA)^{14}$ in conjunction with the PAW potential^{15;16}. The wave functions are expanded in a plane wave basis with an energy cuto of 400 ev, whereas the cuto for the augmentation charges is 645 ev. The Brillouin zone integrations are performed by use of the Monkhorst-Pack scheme¹⁷ with the origin shifted to the point. We utilized a 3 3 1 k point mesh for the geometry optim ization, and 8 1 k point mesh for the DOS calculation. The Si(001)-(2 8 1) surface is modeled adopting a supercell geometry with an atom ic slab of 5 Si layers where term inating hydrogen atom s passivate the Siatom s. The supercell consists of a 4 4 ideal cell, i.e. 80 atom s and 32 H atom s. The Siatom s in the top four atom ic layers are allowed to relax, while the Siatom s in the bottom layer and the adjacent passivating H atom s are xed to simulate bulk-like term ination¹⁸²⁰. The vacuum region is about 19 atom ic layers, which exceeds the length of the 1-propanolm olecule and provides su cient spacing for the present MD simulation. We performed computations on the pure substrate that were intended to exam ine the accuracy of our approach. Thus, we increased the energy cuto to 500 eV and the number of k points to 8 8 1. Neither of these tests led to any appreciable changes of total surface energy; in both cases, the di erence am ounted to less than 12%. The energy barriers characterizing di erent reaction paths were calculated by the climbing Nudged Elastic Band (NEB)^{21 23} method with six in ages, which permits identifying minimum energy paths in complex chemical reactions. Ab initio Molecular Dynamics simulations were performed by use of a Verlet algorithm to integrate Newton's equations of motion. The canonical ensemble was simulated using the Nose $algorithm^{24}$.

As a test, we calculated the structural properties of the free 1-propanolm olecule, and found the obtained bond lengths to be in good agreement with the respective $ndings^{25,26}$. The deviation from these earlier results was found to be less than three per cent. The structures of the isolated 1-propanolm olecule are shown in Fig.1. Further, the calculated

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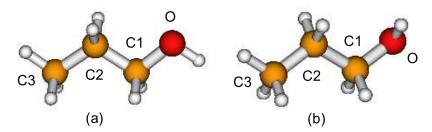


FIG.1: (Color online) 1-propanolm olecule structures in the gas-phase.

TABLE I: The calculated structural parameters of the isolated two isomers of the 1-propanol molecule

	Structure (a)	Structure (b)
d(O H)	0.97	0.97
d(O C1)	1.44	1.43
d(C1 C2)	1.52	1.52
d(C2 C3)	1.53	1.53
\H O Cl	108.5	108.0
\0 C1 C2	108.3	113.5
\C1 C2 C3	112.7	112.7
Dihe(HOC1C2)	179.9	61.3

1-propanolionization energy is within eight per cent of the experim ental value, 10.18 $\,$ 0.06 eV 27

The calculated geometrical parameters are given in Table I, where the unit of the bond length is A .

It should be noted that there are actually ve conformers for the 1-propanolmolecule which di er from each other with respect to the dihedral angles. The isomers (a) and (b) as shown in Fig.1 are the energetically favored species²⁸, and these two conformers are readily interchanged at room temperature, since the OH torsion barriers are quite low. Our calculations involve the structure (a) which deviates from structure (b) by a di erence in binding energy lower than 0.01 ev.

W e further computed energetic and geom etric parameters pertaining to the 2 1 reconstruction of the bare Si(001) surface (its explicit illustration can be found from Fig. 1 in

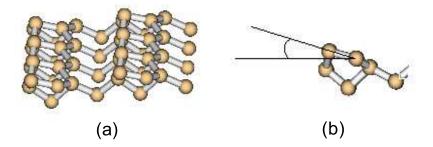


FIG. 2: (Color online) The 2 1 reconstructed silicon surface. The three top layers are shown.

reference²⁹). The 2 1 reconstructed silicon surface is displayed in Figure 2. Figure 2a reveals the three silicon top layers, and Figure 2b illustrates the buckling angle, which is de ned as the angle between the dimer row and the horizontal plane. The Si dimers are oriented along the x axis or [110] direction, and the dimer row s are along the y axis or the [110] direction.

For the 2 1 surface reconstruction with asymmetric Sidimers, the energy gain is 1.6 ev per dimer. The internuclear distance between the two Sicenters is 2.32 A. The distance between two adjacent dimers perpendicular to the row is 3.86 A. The distance between the \up" Siatom of one dimer to the \down" Siatom of the next is 5.57 A. The buckling angle is 18.0. These results agree with existing experimental³⁰ data and other calculations¹⁸.

III. RESULTS AND DISCUSSION

A. The physisorbed and chem isorbed con gurations

In this section, we rst describe the stable physisorbed con gurations of the 1-propanol m olecule on the $Si(001)-(2 \ 1)$ surface for 0.125 M L, where three non-dissociative structures are identified. Subsequently, we consider seven dissociated structures which correspond to them isorbed con gurations. From these seven cases of them isorption, we select the two m ost stable ones. Further, we characterize the modil cation of the bare $Si(001)-(2 \ 1)$ reconstructed surface due to the physisorbed and them isorbed 1-propanolm olecules. M oreover, in an e ort to exam ine which one among the chem isorbed structures is most likely to be observed experimentally, we calculate the energy barriers relevant to the chem isorbed con gurations. The charge density in the plane passing through the oxygen and silicon atom is drawn to show how the 0-Si bond is form ed. The surface band structures, the

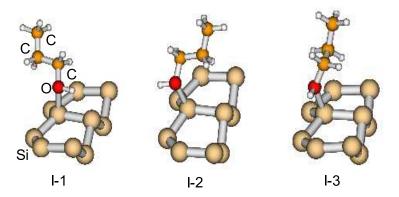


FIG. 3: (Cobronline) Three stable physisorbed con gurations of the 1-propanolm olecule on the Si(001) surface. The yellow (largest), red, orange, and white (sm allest) spheres (from bottom to top) represent the silicon (Si), oxygen (O), carbon (C) and hydrogen (H) atoms, respectively. To illustrate the interaction between the 1-propanolm olecule and the Si(001)-(2 1) surface, we display only a few surface Siatoms. Our simulation includes 16 Siatoms in each layer.

electronic density of states (DOS) and partial DOS projected on the Siatom s and the 1propanol m olecule (or its fragments) are obtained to characterize the interaction between the substrate and the adsorbate.

Here we only focus on the adsorbed structures obtained by an exotherm ic process, i.e., the composite of the surface and the adsorbed species is lower in energy than the free 1-propanol molecule and the bare $Si(001)-(2 \ 1)$ surface in separation from each other. Experimentally, it has been demonstrated that the 1-propanol molecule and its fragments are oriented vertically with respect to the surface¹¹. This adsorption geometry is therefore adopted for our treatment of the physisorbed and chemisorbed congurations.

O ur calculated results con m that the 1-propanolm olecule initially interacts with the $Si(001)-(2 \ 1)$ surface via the formation of a \dative bond" between the oxygen atom and the electrophilic \down" Si atom of the surface dimer. Speci cally, the O - Si bond may be characterized as a covalent connection arising from the lone pair of the O atom. The 1-propanol m olecule remains essentially intact (this motivates our nom enclature I-1, I-2 and I-3 for the physisorbed con gurations) or undissociated on the physisorbed sites, and assumes various orientations of the O -H bond with respect to the Si surface. The obtained structures are shown in F igure 3 which illustrates that the direction of the O -H bond can be parallel (I-1), antiparallel (I-2) or perpendicular (I-3) to the Si dim er. However, the energies of the three con gurations are very close to each other, i.e., the rotation of the 1-propanol

TABLE II: The binding energies in eV /per 1-propanolm olecule and structural parameters of the con gurations shown in Figs.3 and 4. The data are for 0.125 ML coverage. In parenthesis, the binding energy values obtained by a single-dimermodel are indicated.

		I-1	I-2	I-3	F-1	F-2	F-3	F-4	F-5	F-6	F-7	F-8
E _{bii}	nd	0.75	0.72	0.68	2.59	2.89	1.54	1.66	1.66	1 . 65	2,22	2.46
			(0.39)		(2.62)	(3.22)	(1.66)	(1.71)	(1.71)			
d (O	Н)	1.01	0.98	0.98	-	0.97	0.98	0.99	0.97	-	_	_
d(C 1	0)	1.48	1.49	1.49	1.44	-	1.44	1.43	1.43	1,28	_	_
d(C 1	C 2)	1.51	1.51	1.51	1.52	1.53	1.53	1.52	1.52	1.49	1.53	1.53
d (C 2	C 3)	1.53	1.53	1.53	1.53	1.54	1.53	1.53	1.53	1.53	1.54	1.53
d (0	S i)	1.96	1.95	1.99	1.66	1.68	-	_	_	1.79	1.57	1.57
d (C	S i)	_	_	_	-	1.93	1.95	1.94	1.91	-	1.91	1.91
d (H	Si)	-	-	_	1.50	-	1.50	1.50	1.50	1.50	1.50	1.50
d(Si	Si)	2.39	2.38	2.40	2.43	2.44	2.41	2.41	2.43	2.41	2.46	2.44
Buckling	(degree)	8.7	11.0	10.8	1.9	4.1	4.5	5.7	1.6	2.7	1.3	1.9

molecule around the Si-O bond is quite facile.

In the single-dim er cluster calculation, only the physisorbed structure sim ilar to I-2 was considered¹¹, while we include three possible physisorbed con gurations I-1, I-2 and I-3 here. Table II shows that the reported binding energy $(0.39\text{ev})^{11}$ is considerably sm aller than that found in this work (0.72ev). This discrepancy m ight be attributed to the di erence between the single dim er m odel and the periodic approach followed in the present approach.

For the bare $Si(001)-(2 \ 1)$ surface, the buckling angle with the horizontal plane is 18.0. A sa consequence of 1-propanol physicorption, the buckling angles for I-1, I-2 and I-3 become 8.7, 11.0 and 10.8, respectively. For the adjacent Sidim er, the corresponding buckling angles are 17.9, 17.8, and 17.0. As the latter values are close to the angle found for the bare Si(001) surface, 18.0, the interaction between the 1-propanol molecule and the adjacent Sidim er is quite weak.

We have veried that the physisorption in the cases I-1, I-2 or I-3 is a barrierless reaction, which starts from a 1-propanol molecule far from the surface. Once this is physisorbed

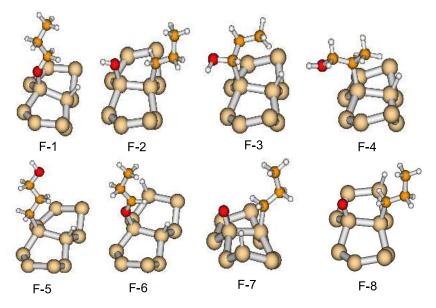


FIG. 4: (Color online) The fragmented chem isorption structures of 1-propanol on the Si (001) surface. For the sake of clarity, we have included only ten Si atom s in this illustration.

and attached to the surface by a \dative bond", the 1-propanol can proceed to react with the surface via a number of pathways, which break one or more molecular bonds to form dissociated congurations of increased stability. The eight principal dissociated structures arising from H atom loss or 0 - C bond cleavage are shown in Figure 4.

The F-1 structure is obtained by breaking the 0-H bond and detaching the H atom until it attaches to the \up" Si atom of the same dimer to form a new H-Si bond. This con guration has the second largest binding energy (2.59ev). The remaining alkoxy fragment is bonded to a Si surface dimer atom, while the separated H atom forms a bond with the other Si atom of the same dimer. The binding energy decreases as the H atom is attached to a Si atom of an adjacent dimer. For the ethanol molecule, the axis of the m ethyl group is almost perpendicular to the Si(001) surface⁴, but in the case of 1-propanol, the corresponding axis includes an angle of about 75 degrees with the surface. Since the considered coverage of 0.125 M L is sparse, the repulsion between the adjacent 1-propanol molecules is negligible. Thus we conclude that the vertical orientation of the 1-propanol molecule is not the result of the repulsion between alkoxy groups, which is consistent with the cases of ethanol adsorption⁴. We have seen that the O atom forms a single polar covalent bond with only one Si atom of the surface dimer, which rejects the localized and directed nature of the Si dangling bond.

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The F-2 con guration is described by C1-O bond cleavage. The OH group and the alkyl fragm ent are bonded to the same Sidim er. If these two fragm ents are attached to adjacent dimers, the binding energy decreases. As Table II shows, the F-2 con guration is therm odynam ically most stable, i.e., it has the largest binding energy (2.89ev).

The F-3, F-4 and F-5 con gurations are characterized by breaking the C1-H, C2-H C3-H bonds, respectively, where the C1, (or C2, C3) atom is bonded to a Siatom and the detached H atom forms a new bond with the other Siatom of the same dimer. From the respective binding energy one nds that the con guration of the C-H cleavage is of lesser stability than both F-1 and F-2.

To exam ine whether the F-1 and F-2 structures undergo further bond nupture, we consider the con gurations F-6, F-7 and F-8. F-6 is described by the cleavage of a C-H bond in F-1, and the H atom is attached to the adjacent dimer. The energy of F-6 is higher than that of F-1 by 0.9 ev. F-7 and F-8 are obtained from F-2 by further dissociating the O-H bond and attaching the corresponding H atom to the 'down' and 'up' Si atom of the adjacent dimer. These structures are energetically less favored than the original F-2 con guration.

In going from I-1 to F-1 (the H atom binding with the 'up' Siatom), a substantial increase in the binding energy is observed. The comparable transition from F-2 to F-7, however, is associated with a large decrease in the binding energy. This dimension from F-2 to F-7, however, is associated with a large decrease in the binding energy. This dimension is related to the fact that I-1 is a physisorbed structure, while F-1 is a chem isorbed one, making plausible its higher stability as compared with I-1. Chem isorption is realized for the configuration F-2, involving saturated covalent bonding of the oxygen atom which forms one bond with the down silicon atom and another one with the hydrogen atom. For the F-7 configuration, in contrast, the hydrogen atom is detached from the oxygen atom which consequently is unsaturated, in plying a decreased binding energy for the F-7 structure. It may be assumed that oxygen in this configuration forms a double bond with the down silicon atom. The latter, however, already form stwo bonds with next layer silicon atom s, and a third one with its silicon dimer partner atom, which leaves a single bond between oxygen and silicon as the only possibility. From an energetic point of view, F-1 and F-2 arem ost stable, corresponding to the tendency of 1-propanol to break the C-0 bond or the 0-H bond. Therefore, the subsequent discussion will be limited to the configurations F-1 and F-2.

To see that increasing the plane wave basis (or the energy cuto $\)$ has only a slight e ect on the above adsorption energies, we have calculated the adsorption energies for the I-1, I-2,

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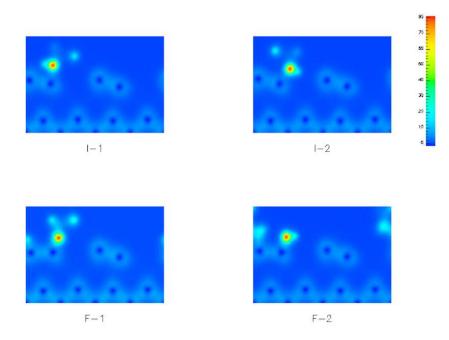


FIG. 5: (Cobr online) The charge density in the plane extended in the directions [110] and [110] for the con gurations I-1, I-2, F-1 and F-2. The unit for the charge density is 0.01 e/A^3 . The red zone is due to the higher charge density of the oxygen atom, the blue spots correspond to the silicon charge density. The charge density between the 0 and Si atoms shows the polar 0 - Si bond.

F-1 and F-2 con gurations at 500eV. If the energy cuto is 400ev, the adsorption energies for the same con gurations are 0.75, 0.72, 2.59 and 2.89 eV, respectively. W hen the energy cuto is 500ev, the corresponding energies are 0.75, 0.71, 2.56, and 2.91 eV. The di erence between the two sets of results amounts to less that 1.2%.

The charge density in the plane passing through the oxygen and the silicon atom (extended in the directions [110] and [110]) is shown in Fig.5. It is calculated within pseudopotential framework. The analysis of the charge density clearly shows that a polar \dative bond" for the physisorbed structures I-1 and I-2 (O-Sibond lengths for them are 1.96 A and 1.95 A) and the polar covalent bond for chem isorbed structures F-1 and F-2 (O-Sibond lengths for them are 1.66 A and 1.68 A) have been form ed.

R eaction	E _b (eV)	$\rm E_{TS}$ (eV)
1-propanol+ Si(001) ! I-1	0	-
I-1 ! F-1 (0 +1 breaking)	0.05	-0.70
I-2 ! F-2 (C-0 breaking)	1.34	0.62
F-1! F-6	2.9	0.31

TABLE III: The energy barriers E_b , and transition state energy levels E_{TS} with respect to the energy of the 1-propanolm olecule and the Si(001) surface in separation from each other

B. Energy barriers

To assess which them isorbed structure is most likely to be observed experimentally, we have calculated the energy barriers relevant to the them isorbed congurations. Table III shows the energy barriers for the respective reactions. For the physisorbed structures I-1, I-2 and I-3, the reaction proceeds without barrier. For the cases of them isorption, we have calculated the energy barriers for the processes that lead from I-1 to F-1, I-2 to F-2 and F-1 to F-6, respectively. The energy barriers have been calculated by the climbing Nudged E lastic B and m ethod⁽²¹⁾ 23, where six equidistant in ages have been used.

For the transform ation to the F-1 con guration, I-1 is the most favorable initial structure since its 0 H bond is already oriented parallel to the Sidim er row. This reaction is a proton transfer process from oxygen to the electron-rich, nucleophilic up silicon atom of the dimer. The I-1 to F-1 reaction is characterized by an energy barrier of 0.05 ev. The binding energy of I-1 is 0.75 ev which in plies that the barrier for the whole process, i.e. adsorption into the I-1 structure followed by transition to the F-1 structure, is below the initial energy, nam ely the of the free 1-propanolm olecule and a bare Si(001) surface. Since the binding energy of F-1 is 2.59 ev, the I-1 ! F-1 process is exotherm ic.

From the physisorption case I-2 to con guration F-2, involving the breaking of a C-0 bond, the energy barrier is 1.34 ev. The binding energy of I-2 is 0.72. Therefore, the transition state energy is higher than the reference energy of the free 1-propanolm olecule and the bare Si(001) surface. The binding energy of F-2 is 2.89 ev, m aking the I-2 ! F-2 process exotherm ic too. Thus the 0-C bond cleavage is therm odynam ically stable, but the 0-H bond cleavage is kinetically favored. In other words, the 0-C bond cleavage has the

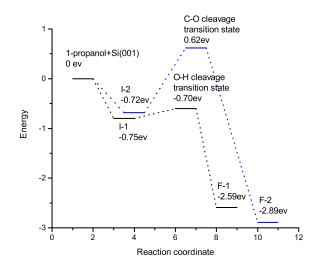


FIG.6: (Color online) The relative energy levels along the 0-C and 0-H cleavage reaction paths.

highest binding energy, while the O-H bond cleavage has a smaller energy barrier than the O-C bond cleavage. This con rms, on the basis of a more adequate periodic model, the conclusion reached by Zhang et. al.¹¹ in the framework of a nite cluster approach. The relative energies along the O-C and O-H cleavage reaction paths are schematically illustrated in Fig.6.

Zhang et. al^{11} suggested that the initial O-H bond cleavage m ight be followed by a hydrogen elimination reaction to result in aldehydes and hydrogen. Table III shows that the energy barrier for the transition from the O-H cleavage con guration F-1 to the con guration F-6 is relatively high. One concludes that the respective reaction is not preferred. Similarly, the transition from F-2 to F-7 con guration is not favored.

The undissociated structures I-1, I-2 and I-3 can be interpreted as m etastable precursors for the m ore stable F-1 con guration. These precursors do not have su cient binding energy at room temperature to compete as observable reaction products, i.e. the cleavage of H is too fast for any of the physisorbed structures to be observed. The MD simulation outlined below gives additional support to this interpretation.

C. Band Structure

A sketch of the eight relevant Si dim er units in the top Si layer is shown in Fig. 7 for unam biguous reference, where the horizontal (vertical) corresponds to the [110] ([110]) directions, respectively. For 0.125 M L, the 1-propanolm olecule or its fragm ents are adsorbed

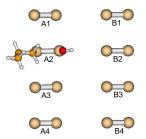


FIG. 7: (C olor online) The labels and positions of eight dimmer units in the top Si layer, where the horizontal direction is along [110] and the vertical one is along [110].

to the A2 dim er.

The up Si atom s are located at the left dim er ends, the down Si atom s at the right. However, as described above, after the adsorption of the 1-propanolm olecule to the down Si atom, the latter is raised, i.e., the buckling angle decreases.

The surface band structures within the fundamental band gap of the silicon for the congurations I-1, I-2, F-1 and F-2 for 0.125 M L, are depicted in Fig. 8. The k points $_{J}K$, $_{J}^{0}$ are four vertices of the square of the quarter part of the surface B rillouin zone (the relative positions of $_{J}K$, $_{J}^{0}$ points can be seen from Fig.3 in the work of R am stad et. al.²⁹).

Fig. 8 reveals that there are seven, nine, eight and eight surface bands within the fundam ental band gap of silicon for the I-1, I-2, F-1 and F-2 con guration, respectively. The remaining valence (conduction) bands lie in the lower (higher) shaded area. In the I-1 conguration, for the valence bands (occupied), the top one is labeled I-1-01, and the next lower one is I-1-02, etc.. For the conduction band (unoccupied), the bottom one is referred to as I-1-U1, the higher ones are I-1-U2, I-1-U3, I-1-U4, and the highest one is I-1-U5. The same nom enclature is used for the surface bands of the other three con gurations.

The two highest surface valence (01 and 02) and the two lowest surface conduction bands (U1 and U2) contain the information about the adsorption and are thus sensitive to the structural features of the surface. The conduction bands U4 and U5, for instance, exhibit the same atom ic orbital composition for all four congurations, I-1, I-2, F-1 and F-2. It is therefore su cient to consider only the top two occupied valence bands (01,02) and bottom two unoccupied conduction bands (U1,U2), and them ain contributions to these four bands are shown in Table IV for the congurations I-1, I-2, F-1 and F-2. Table IV indicates that the band I-1-01 contains the information about the 1-propanol adsorption. The A1

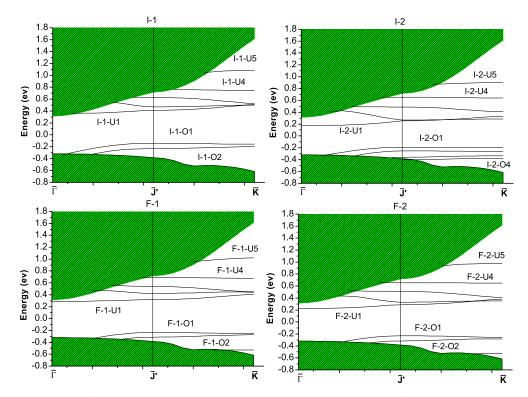


FIG. 8: (Color online) Surface band structures for the con gurations I-1, I-2, F-1 and F-2 at 0.125 M L. The shaded areas represent the projected bulk band structure, while surface states are represented as solid lines.

and A 3 contributions to the valence band I-1-01 are an electronic ngerprint of the adjacent dimers, while the 1-propanol physisorption leaves their geometric structure una ected, as rejected by their buckling angles.

Here we note that within the fundam ental band gap of silicon, there is no conduction band for a Si-O bonding due to the adsorbate. In case of the acetonitrile adsorption on the silicon surface¹⁹, in contrast, a conduction band with both Si and N contributions is found within this gap, which indicates that the acetonitrile electronic interaction with the silicon substrate might be stronger than that for 1-propanol.

D. Density of States

The electronic density of states (DOS) as well as the partial DOS projected on Siatom s and the 1-propanolm olecule (or its fragments) for the physisorbed con gurations I-1 and I-2, and the chem isorbed con gurations F-1 and F-2 are shown in Fig. 9 and Fig.10. The top,

Bands	m ain com positions
I-1-0 1	3pz [up Si (A 1, A 2, A 3)]
I-1-0 2	3p _x ,3p _x [up Si (A 1-A 4,B 1-B 4)], 3p _z [up Si (A 4)]
I-1-U 1	3pz [down Si (A 1, A 3, A 4, B 1-B 4)]
I-1-U 2	3pz [down Si (A 1, A 3, A 4, B 1-B 4)] + 3pz [Siin ad jacent
	layer which form bonds with down Si (Al-A4,Bl-B4)]
I-2-01	3pz [up Si (A2)]
I-2-0 2	3pz [up Si (A 1,A 3)]
I-2-U 1	3pz [down Si (B1,B2,B3,B4)]
I-2-U 2	3s,33pz [down and up Si (B1,B2,B3,B4)]
F-1-01	3pz [up Si (A1,A3,A4,B1,B3,B4)]
F-1-02	3s,3p _z [up Si (B2)]
F-1-U1	3p _z [down Si (A1,A3,A4,B1,B2,B3,B4)]
F-1-U2	$3p_z$ [down Si (A 1,A 3)], $3s_r 3p_z$ [up Si
	(B2,B4)], 3pz [down Si(B2,B4)]
F-2-01	3pz [up Si (A 4, B 4)]
F-2-02	3s,3pz [up Si (A 1,A 3,B 1,B 3)]
F-2-U1	3p _z [down Si (B1,B2,B3,B4)]
F-2-U2	3p _z [down Si (A 1, A 3)]

TABLE IV : A tom ic composition of the highest lying valence and low est conduction bands for the congurations I-1, I-2, F-1 and F-2. In parenthesis, the contributing atom s are indicated.

m iddle and bottom layers represent the DOS of the total slab, the partial DOS projected on Si and the 1-propanolm olecule (or its fragments for chem isorbed structures), respectively. The partial DOS projected on the 1-propanolm olecule (or its fragments) is much lower in magnitude than the DOS of the total slab for 0.125M L coverage. To show its features manifestly, we have rescaled this distribution (vertical axis) (see Figs. 9 and 10), and the rescale factor is 10.

We consider the DOS with special emphasis on the peaks around the Ferm i level and some characteristic peaks. The partial DOS projected on the Siatom s has alm ost the same

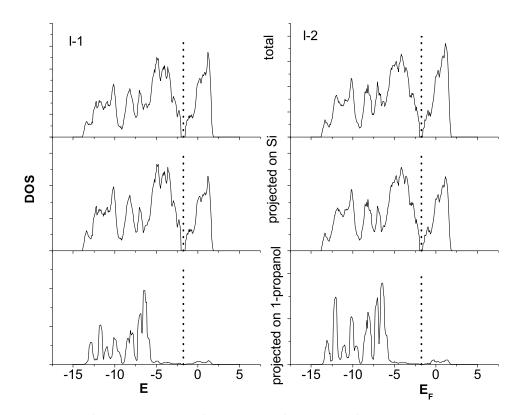


FIG. 9: The electronic DOS and partial DOS projected on Si and 1-propanol molecule for the physisorbed con gurations I-1 and I-2 at 0.125 M L 1-propanol coverage. The vertical dotted lines represent the positions of the Ferm i level.

pro le as that of the DOS of the total slab, which indicates that, for 0.125 M L coverage, the total DOS is dominated by the Si(001) surface states.

In the following discussion, we focus on the two projected partial DOS distributions. The main components of the peaks of the partial DOS distributions projected on the Siatom s and 1-propanol (or its fragments) are indicated in Table V for the con gurations I-1, I-2, F-1 and F-2

C om paring the partial D O S distributions projected on the 1-propanol molecule for the con gurations I-1 and I-2 (see Table V), we see that the second peak is the same for both con gurations, but the rst and third peaks are di erent which rejects the fact that the O-H bond direction for I-2 is by 180 rotated with respect to that of the con guration I-1. C om paring the D O S of the total slab, the partial D O S projected on the Siatom s as well as on the 1-propanolm olecule (see Figs. 9 and 10) we ind that near the Fermi level, the D O S is dom inated by states that stem from the Si(001) substrate, but at low energy (far below the Fermi level), the total D O S is modulated by the projected on the 1-propanoladmixture (or

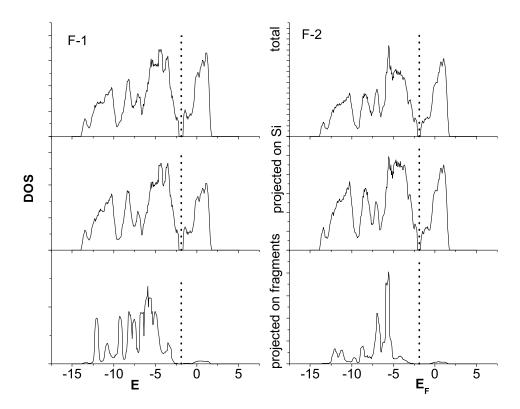


FIG. 10: The electronic DOS and partial DOS projected on Si and 1-propanol fragments for the chem isorbed con gurations F-1 and F-2 at 0.125 M L 1-propanol coverage. The vertical dotted lines represent the positions of the Ferm i level.

its fragm ents).

IV. DEPENDENCE ON THE LEVEL OF COVERAGE

Taking advantage of the slab approach, we will discuss in the following the dependence of the binding energy of the four basic congurations (I-1, I-2, F-1, F-2) on the coverage of the 1-propanolm olecules. First, we will consider the basic congurations I-1, I-2, F-1 and F-2 with the coverage levels 1.00M L, 0.5M L, 0.25M L and 0.125M L, which corresponds to one 1-propanolm olecule attached to one, two, four and eight dimers, respectively. Table V I shows the binding energies of the four congurations of 1-propanol on the Si(001)-(2 1) surface.

Table VI shows that the binding energies per 1-propanolm olecule for the physisorbed congurations I-1 and I-2 decrease with increasing coverage. This trend appears quite natural since increasing concentration of the adsorbed m olecules on the Si(001) surface results in enhanced interaction between the molecules and hence weakens their bond with the substrate.

TABLE V: The main components of the peaks of the partial DOS distributions projected on the Si atom s and 1-propanol (or its fragments) for the con gurations I-1, I-2, F-1 and F-2. The 3p represents $3p_x$, $3p_y$ and $3p_z$.

Con gurations	peak 1	com ponent	s peak 2	com ponents	s pe	eak 3	com ponents
	position	ofpeak 1	position	ofpeak 2	pos	sition	ofpeak 3
partial D O S	-3.0 -5.0ev	Зp	1.4ev	3p _x ,3p _y	-11,2	-12.5ev	Зр
[Si]		[Si]		[Si]			[Si]
I-1 partialDOS	-11.7ev	2p _x ,2p _y	-7.1ev	2p _z	-6	.4ev	2p _x [C 3],
[1-propanol]		[O]		[C 2,C 3]			2py [C1]
partialDOS	-3.0 -5.0ev	Зp	1.4ev	3p _x ,3p _y	-11.2	-12 . 5ev	Зр
[Si]		[Si]		[Si]			[Si]
I-2 partialDOS	-12.1ev	2py	-7.1ev	2pz	-6	.5ev	2py
[1-propanol]		[O]		[C2,C3]			[C 2,C 3]
partialD0S	-3.0 -5.0ev	Зр	1.4ev	3р _х , 3р _у	-11,2	-12.5ev	Зр
[Si]		[Si]		[Si]			[Si]
F-1 partialDOS	-9.3ev	2p _z [C1],	-6.7ev	2p _x [C3],	-6	.1ev	2py [C3],
[H+alkoxy]		2p _x [D]		2py [0]			2p _z [C2]
partialDOS	-3.0 -5.0ev	Зр	1.4ev	3p _x ,3p _y	-11.2	-12 . 5ev	Зр
[Si]		[Si]		[Si]			[Si]
F-2 partialDOS	-12.5ev	2p _x ,2p _y	-6.8ev	2py [C1],	-5	.5ev	2p _x ,2p _y
[OH+alkyl]		[O]		2pz [C3]			[C 2,C 3]

TABLE VI: Binding energies of the adsorbate on Si(001) in eV/per 1-propanolm olecule at four coverage levels

C overage	I-1	I-2	F-1	F-2
0.125	0.76	0.72	2.59	2.89
0.250	0.73	0.70	2.57	2.90
0.500	0.68	0.67	2.55	2.91
1.000	0.41	0.37	2.34	2.85

Coverage I–1	!F−1(E _b)	I-1! F-1(E _{TS})	I-2! F-2(E _b)	I-2! F-2(E _{TS})
0.125	0.05	-0.70	1.34	0.62
0.250	0.02	-0.72	1.34	0.63
0.500	0.02	-0.65	1.32	0.65
1.000	0.05	-0.36	121	0.84

TABLE VII: Energy barriers E_b and transition state energy levels E_{TS} , for the dissociation processes I-1! F-1 and I-2! F-2 at four levels of surface coverage. The reference for the indicated energy values is the energy of the separated subsystem s.

The binding energy for the chem isorbed structure F-1 decreases with increasing coverage too. This may be related to the fact that the alkoxy fragment has similar transverse dimensions as the 1-propanol molecule. However, the binding energy for the chem isorbed con guration F-2 exhibits very little change with the variation of the coverage. This observation is ascribed to the strengthened interaction between the alkyl fragments and OH groups on dimension with increasing coverage, counteracting the destabilization trend due to the enhanced alkyl density.

The dependence of the energy barriers on the 1-propanol coverage in the interval [0.25 M L, 1.0 M L] is illustrated by Table V II, which contains the energy barriers E_b and transition state energy levels E_{TS} with respect to the energy of 1-propanol and Si(001) in isolation from each other. Two processes correspond to 0 H bond and C-O bond scission.

Here we point out that the 1-propanole molecules are placed on the surface uniform ly, and all the molecules dissociate simultaneously. From E_b values for the 0-H and C-O bond nupture in Table V II, we not that the energy barriers for the 0-H bond scission are only slightly a ected by the level of coverage. However, the energy barriers for the C-O bond breaking (E_b) decrease with the increasing coverage.

From Table VI, the bonding of the chem isorbed structure F-1 (O H bond scission) is weakened as the coverage increases, and Table VII reveals that the energy barrier with respect to the O H bond rupture (E_b) becomes higher at 1.00M L coverage. Thus, the probability of O H bond scission is somewhat reduced at this level. On the other hand, the binding energy for the C-O bond cleavage changes very little as the coverage is varied, while the energy barrier with respect to the rupture of the C-O bond (E_b) has its minimal value at

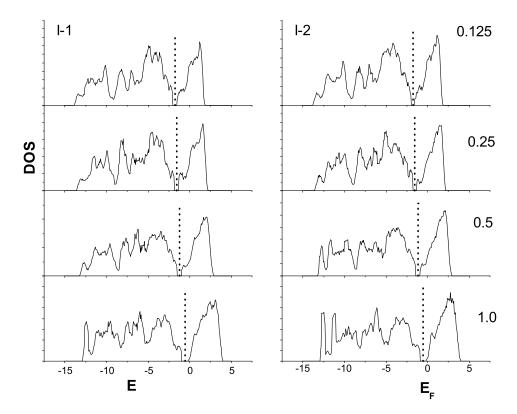


FIG.11: The DOS of the full slab for the physisorbed con gurations I-1 and I-2 at 0.125, 0.25, 0.5 and 1.0 ML.

1.00M L. This suggests that at a high coverage level, a sm all am ount of C-O cleavage m ight occur, as supported by the experimental observation at high surface coverage⁹.

The DOS distributions of the 1-propanol molecules (or its fragments) at the coverage levels considered in this work are shown in Fig. 11 for the physisorbed con gurations I-1 and I-2, and Fig. 12 for the chem isorbed con gurations F-1 and F-2.

The partial D O S projected on the 1-propanolm olecule for the physisorbed I-1 structure at 0.125M L exhibits peaks at -6.4 ev and -7.1 ev which are traced back to 2p orbitals of the carbon atom s C 1,C 2 and C 3, and the peak at -11.7 ev originates from the $2p_x$ and $2p_y$ orbitals of the oxygen atom . W ith increasing coverage the peaks at -6.4 eV, -7.1 eV and -11.7 eV are found to grow if the substrate peak between -3.0 ev and -5.0 eV is taken as reference, which is the expected behavior upon 1-propanol deposition enhancement. This conclusion applies for all the physisorbed and chem isorbed con gurations.

Form ore quantitative analysis of the D O S distributions, we exam ined the dependence of the energy gap on the 1-propanol coverage (or its fragm ents). Table V III shows the obtained values for the physisorbed con gurations I-1 and I-2, and the chem isorbed con gurations

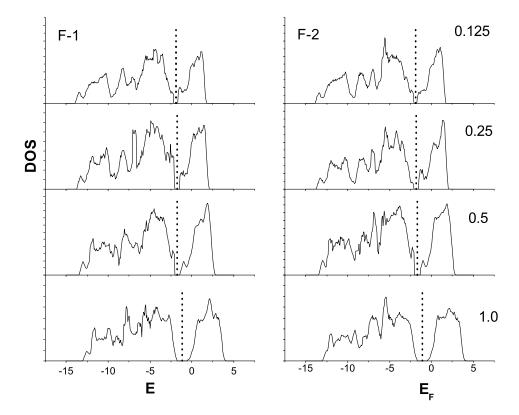


FIG.12: The DOS of the full slab for the chem isorbed con gurations F-1 and F-2 at 0.125,0.25, 0.5 and 1.0 M L.

TABLE VIII: Energy gaps E (eV) of the Si(001)-(2 1) pure surface compared to those of the 1-propanol adsorption structures I-1,I-2,F-1, and F-2 on Si(001) at four levels of coverage

Coverage S	Sisurface	e I-1	I-2	F-1	F-2
0.125	0.46	0.53	0.40	0.53	0.40
0.250	0.46	0.53	0.47	0.60	0.60
0.500	0.46	0.53	0.53	0.80	0.73
1.000	0.46	0.80	0.73	1.27	1.20

F-1 and F-2 with 0.125M L, 0.25M L, 0.5M L and 1.0M L.

The energy gap for the Si(001)-(2 1) surface is 0.46 ev, see Table V III, which is in keeping with experiment (the corresponding experimental value is about 0.6 ev³¹). The bcalDFT and GGA procedures tend to underestimate the energy gap of sem iconductors by up to 25% ³². Table. V III shows that the energy gaps increase with the level of coverage, which rejects a growing degree of saturation of the silicon dangling bond as induced by the

1-propanol molecules. As a consequence of a higher number of oxygen atoms attached to the surface, and, by the same token, of dative bonds (for the physisorbed con gurations I-1 and I-2) or covalent bonds (for the chem isorbed con gurations F-1 and F-2) between oxygen atoms and silicon atoms, the surface turns increasingly insulating, i.e., the energy gap widens.

V. ROOM TEMPERATURE MOLECULAR DYNAM ICS CALCULATIONS

The energy barrier computations have shown that the physisorbed 1-propanolm olecule reacts with the Si(001)-(2 1) surface by cleavage of the 0 H bond. Since the zero tem perature transition state analysis m ay not be able to access all of the relevant phase space volume, we perform a nite temperature ab initio MD simulation to take into account additional possible reactions at T = 300K. The 1 2 cell is adopted to carry out the MD simulation (the 2 2 cell was used as well, and the results from both approaches were found to agree). In the nite tem perature M D calculations all atom s, including the passivating H atom s at the bottom of the slab, are allowed to move. In this manner, a large tem perature gradient can be avoided. Lattice parameters are expanded according to the tem perature under study using the experim ental therm alexpansion coe cient in order to prevent the lattice from experiencing internal therm al strain²⁰. The starting con guration is the physisorbed one I-1, see Fig. 3, the 0 -H and 0 -C bond lengths are 1.01 A and 1.48 A, respectively. The I-1 physisorbed structure is heated to 300K (room tem perature) in 9000M D step (9.0 ps, i.e., each step takes 1 fs), followed by another 3000M D steps at 300K to evolve the system under conditions of them al equilibrium. D isplaying the free energy of the system as a function of the evolution time, we assess if the system has reached its equilibrium. As illustrated by Figure 13, the free energy uctuates very little after 10ps, which shows the system is at equilibrium. In Figs. 13, 14 and 15, every data point represents an average result over an interval of 300M D steps. In this way, high frequency components due to therm alm otion³³ are ltered out.

We consider the time variation of the O-Cl and Si-Cl bond lengths in the MD calculation, which are represented in Fig. 14. It is seen that the O-Cl bond is not ruptured in the process of the simulation. For times shorter than 6ps, the distance between the Cl and the up Si atom uctuates around 4.25 A; between T = 6ps and T = 7ps, it reduces by 1 A, and

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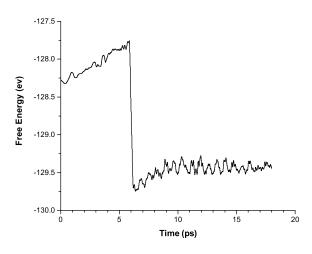


FIG. 13: T in e variation of the free energy in the MD simulation. An average over every 300MD steps has been taken to liter out high therm al frequency components.

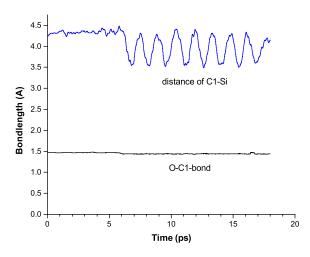


FIG. 14: (Color online) T in e variations of the Si-C1 distance and O-C1 bondlength in the MD evolution. An average over every 300MD steps has been taken to liter out high therm al frequency components.

after T = 7ps, it oscillates around 4.0 A, which shows that no bond between C1 and the up Si is form ed. This behavior rules out the chem isorbed con guration F-2 as an equilibrium structure.

On the other hand, the time variation of the O-H and SiH bond lengths in the MD simulation, as drawn in Fig. 15, illustrates that before T = 6ps, the O-H bond length is about 1.01 A and the SiH bond length oscillates around 2.25 A. In the period of 6ps 7ps, the O-H bond length elongates up to 3.75 A, and the SiH bond length shortens to 1.48 A. This marked change indicates a transition from the metastable physisorbed phase I-1 to the \stable" chem isorbed phase F-1. The characterization as stable for the F-1 structure only

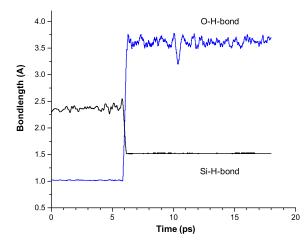


FIG.15: (Color online) T in e variation of the O-H and SiH bondlength in the evolution that O-H bond is breaking and SiH bond is form ing An average over every 300M D steps has been taken to liter out high them al frequency components.

m akes sense at room temperature, since the chem isorbed phase F-2 ism uch more stable than F-1 at still higher temperature. A fler 7ps, the 0-H bond length oscillates with decreasing amplitude, and the SiH bond length reaches its equilibrium value of 1.48 A. Fig. 15 shows that 0-H bond scission occurs and the SiH bond form s between T = 6ps and T = 7ps. The equilibrium structure is the chem isorbed con guration F-1, i.e., the 0-H bond is broken (see Fig.4), which is consistent with the energy barrier calculation at zero temperature.

Inspection of the MD simulation results shows that the 0 H bond is broken. The H atom is detached and reattaches to the \up" silicon atom of the same dimer (dimer A2) to form a new H-Si bond. A fler 7ps, all atoms oscillate around their stable equilibrium positions. Another method of performing the MD simulations consists in setting an initial temperature T equal to 300K without any heating and letting the system evolve at this temperature. Following this avenue, we arrive at the same conclusions as reported above.

VI. SUMMARY

We have performed a study on the physisorption and chemisorption of 1-propanol molecules on the Si(001)-(2 1) surface from rst principles. Phenomena related to the geometric, electronic, energetic and fragmentation pathways have been investigated within three-dimensional periodic boundary conditions. Speci cally, we have shown that the 1-propanolm olecule initially interacts with the Si surface through formation of a dative bond.

Subsequently, the physisorbed 1-propanol m olecule reacts with the surface by cleavage of either the 0-C or the 0-H bond. The 0-C bond cleavage is therm odynam ically stable, but the 0-H bond cleavage is kinetically favored. We characterized the geometric modil cation of the Si(001)-(2 1) surface in response to physisorption as well as chem isorption, which cannot be described by use of a single-dimer cluster model.

We have rst calculated the band structure and the DOS for four con gurations, dem onstrating that the occupied bands within the fundam ental band gap of the silicon are com – posed of the up Si atom s, and the unoccupied bands originate from the down Si atom s. No conduction band within the fundam ental band gap could be associated with SiO bonding. This feature distinguishes the present case from that of aceton itrile adsorption on the silicon surface¹⁹. For aceton itrile adsorption, a conduction band within this gap has been assigned to SiN bonding, which shows that the aceton itrile electronic interaction with the silicon substrate m ight be stronger than that of 1-propanol. The peaks around the Ferm i level and other peaks related to adsorption for the DOS and partial DOS distributions were discussed. It has been shown that the DOS near the Ferm i level is dom inated by the states from the Si(001) surface, but at low energy (far below the Ferm i level) the DOS is modulated by the 1-propanol contribution, or that of its fragm ents.

W e have analyzed the dependence of the various properties (binding energy, energy barrier, density of states (DOS), energy gap) for the con gurations I-1, I-2, F-1 and F-2 on the coverage levels 0.125M L, 0.25M L, 0.5M L and 1.0M L. From this research, the binding energies of the physisorbed con guration I-1, I-2 and chem isorbed con guration F-1 decrease with increasing coverage. This trend appears plausible since increasing concentration of 1-propanol m olecules on the Si(001) surface results in enhanced repulsion between the m olecules and hence destabilization. How ever, the binding energy for the chem isorbed con-

guration F-2 is found to be rather insensitive to the variation of the coverage level. The energy barrier with respect to 0 H bond scission at four levels of coverage changes slightly, and reaches its maximum within the [0.25 M L, 1.0 M L] interval at 1.00M L. However, the energy barriers with respect to the C-O bond rupture (E_b) decrease with increasing coverage. Thus, we found the bonding of the chem isorbed structure F-1 (O H bond scission) destabilized at higher coverage, while the energy barrier is highest at 1.00 M L, suggesting a reduced probability of O H bond scission at the 1.00M L level. On the other hand, the binding energy for the C-O bond breaking structure changes very little with the level of coverage, while the energy barrier with respect to the C-O bond nupture (E_b) adopts its minimal value at 1.00 M L. One concludes that conditions of high coverage favor C-O cleavage, and a small admixture of this chemisorption channel may be observable at 1.0 M L⁹. The DOS showed that upon increasing 1-propanol deposition, the peaks due to the 1-propanol molecular orbitals grow in intensity, and the substrate features diminish. Also, with enhanced coverage, the energy gaps widen which indicates increasing saturation of the silicon dangling-bonds by the 1-propanol molecules. The planar 1-propanol density on the Si(001) surface thus represents a parameter that allows to alter the nature of the surface from semiconducting to insulating.

Finally, recording the time variation of the O-H and SiH bond lengths by means of ab initio M D simulation demonstrated that the O-H bond length is spontaneously ruptured at room temperature, and the dissociated H atom forms a SiH bond. The nal equilibrium structure at room temperature is the chemisorbed con guration F-1. The observed O-Hbond rupture is in accordance with the energy barrier calculation at zero temperature.

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